



Seiko Seiki STP-600, 1000, 2001

Technical Specifications

Ultra High Vacuum (UHV) - Corrosion Resistant (C) Tritium (T)-Metal Sealed CF Flange

	STP600 STP600C STP600T	STP1000 STP1000C STP1000T	STP2001 STP2001C STP2001T		STP600 STP600C STP600T	STP1000 STP1000C STP1000T	STP2001 STP2001C STP2001T
Inlet flange:				Max. continuous outlet pressure, mbar (torr): water cooled air cooled ambient cooled			
ISO	ISO160	ISO200	ISO250				
CF	CF8 (DN160CF)	CF10 (DN200CF)	CF12 (DN250CF)				
ASA		ASA6			0.13(0.1)	0.13(0.1)	0.13(0.1)
Outlet Flange:				Throughput at max. inlet pressure (sccm N₂)			
UHV, C, H-C Series	NW40	NW40	NW40		4.0	5.7	12
T Series	CF35	CF35	CF70				
Purge port:				Rotational speed (r. min⁻¹)			
C, H-C Series	NW10	NW10	NW10		35000	35000	27000
Emergency vent valve	N/A	N/A	NW10				
Pumping speed (ls⁻¹):				Ramp up time (mins):			
N ₂	650	1000	2000		6	6	7
He	600	900	1800				
H ₂	550	800	1600	Vibration μm (P-P)	>0.01	>0.01	>0.01
Compression ratio:				Maximum inlet flange temp (°C)			
N ₂	>10 ⁸	>10 ⁸	>10 ⁸		>120	>120	>120
He	2 x 10 ⁵	2 x 10 ⁵	2 x 10 ⁵				
H ₂	10 ⁵	10 ⁵	10 ⁵	Weight, kg (lbs):			
				pump	30(66)	31(68)	63(139)
				controller	21(46)	21(46)	40(88)
Ultimate pressure (mbar)	10 ⁻¹⁰	10 ⁻¹⁰	10 ⁻¹⁰	Power consumption (VA):			
				start up	1200	1200	2600
				continuous	300-1000	300-1000	1000
Max. continuous inlet pressure, mbar (torr):				Power supply (Hz)			
water cooled				200-240V	200-240V	200-240V	
air cooled				100-120V	100-120V	100-120V	
ambient cooled	10 ⁻⁴	10 ⁻⁴	10 ⁻⁴	Cooling water requirements at 5-25°C, l min⁻¹ (US gal min⁻¹)	option	option	option
				Backing pump	E2M18	E2M28/30	E2M40



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Features & Benefits

- oil free
- low vibration
- high reliability
- maintenance free
- increased life
- electromagnetics for bearings
- advanced controller design
- compact design
- small footprint
- advanced rotor technology
- installation in any orientation

Applications

- plasma etch
- electron cyclotron resonance
- film deposition
- ion implantation
- sputtering
- MBE
- diffusion
- photo resist stripping
- crystal growth
- water inspection
- load-lock chambers

Recommended controller

- controllers: SCU-600 • SCU-1000 • SCU-2001
- backing pump: E2M18 • E2M28 • E2M30 • E2M40